



## UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE  
 United States Patent and Trademark Office  
 Address: COMMISSIONER FOR PATENTS  
 P.O. Box 1450  
 Alexandria, Virginia 22313-1450  
 www.uspto.gov



Bib Data Sheet

CONFIRMATION NO. 4946

SERIAL NUMBER 10/660,151	FILING DATE 09/11/2003  RULE	CLASS 438	GROUP ART UNIT 2812	ATTORNEY DOCKET NO. 004994 ALRT/ETCH/SILICON
-----------------------------	---------------------------------------	--------------	------------------------	---

## APPLICANTS

Songlin Xu, Fremont, CA;

Thorsten B. Lill, Santa Clara, CA;

Yeaer Arthur Chen, Fremont, CA; Mohit Jain, San Jose, CA;

Nicolas Gani, Milpitas, CA;

Shing-Li Sung, Hsin-Chu, TAIWAN;

Jitske K. Kretz, San Jose, CA;

Meihua Shen, Fremont, CA;

Farid Aboomeri, Pleasanton, CA;

## \*\* CONTINUING DATA .....

This appln claims benefit of 60/444,340 01/31/2003

## \*\* FOREIGN APPLICATIONS .....

none, of

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 12/05/2003

Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY CA	SHEETS DRAWING 7	TOTAL CLAIMS 20	INDEPENDENT CLAIMS 2
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged	Examiner's Signature	Initials		

## ADDRESS

44182

MOSER, PATTERSON &amp; SHERIDAN, LLP

APPLIED MATERIALS INC

595 SHREWSBURY AVE

SUITE 100

SHREWSBURY, NJ

07702

## TITLE

Process for etching polysilicon gates with good mask selectivity, critical dimension control, and cleanliness